

requirements for the safe handling of flammable, combustible, explosive, reactive, or hazardous materials.

Shutdown means the cessation of operation of an affected source, any process vessels within an affected source, or equipment required or used to comply with this subpart if steps taken to cease operation differ from those under routine procedures for removing the vessel or equipment from service. Shutdown also applies to the emptying and degassing of storage tanks.

Small control device means a control device that controls total HAP emissions of less than 10 tpy, before control.

Soluble HAP means the HAP listed in Table 8 of this subpart.

Startup means the setting in operation of a new affected source. For new equipment added to an affected source, including equipment required or used to comply with this subpart, startup means the first time the equipment is put into operation. Startup includes the setting in operation of equipment any time the

steps taken differ from routine procedures for putting the equipment into operation.

Storage tank means a tank or other vessel that is used to store organic liquids that contain one or more HAP as raw material feedstocks or products. The following are not considered storage tanks for the purposes of this subpart:

(1) Vessels permanently attached to motor vehicles such as trucks, railcars, barges, or ships;

(2) Pressure vessels designed to operate in excess of 204.9 kilopascals and without emissions to the atmosphere;

(3) Vessels storing organic liquids that contain HAP only as impurities;

(4) Wastewater storage tanks; and

(5) Process vessels.

Total organic compounds or (TOC) means the total gaseous organic compounds (minus methane and ethane) in a vent stream.

Wastewater storage tank means a stationary structure that is designed to

contain an accumulation of wastewater and is constructed primarily of nonearthen materials (e.g., wood, concrete, steel, plastic) which provide structural support.

Wastewater stream means water that is discarded from miscellaneous coating manufacturing operations through a POD, and that contains an annual average concentration of total partially soluble and soluble HAP compounds of at least 1,600 ppmw at any flow rate. For the purposes of this subpart, noncontact cooling water is not considered a wastewater stream.

Work practice standard means any design, equipment, work practice, or operational standard, or combination thereof, that is promulgated pursuant to section 112(h) of the Clean Air Act.

Tables to Subpart HHHHH of Part 63

As required in § 63.8005, you must meet each emission limit and work practice standard in the following table that applies to your process vessels:

TABLE 1 TO SUBPART HHHHH OF PART 63—EMISSION LIMITS AND WORK PRACTICE STANDARDS FOR PROCESS VESSELS

For each . . .	You must . . .	And you must . . .
1. Portable process vessel at an existing source.	Equip the vessel with a cover or lid that must be in place at all times when the vessel contains a HAP.	Non applicable
2. Stationary process vessel at an existing source.	<p>a. Equip the vessel with a cover or lid that must be in place at all times when the vessel contains a HAP; or.</p> <p>b. Equip the vessel with a tightly fitting vented cover or lid that must be closed at all times when the vessel contains HAP.</p>	<p>i. Considering both capture and any combination of control (except a flare), reduce emissions by ≥ 75 percent by weight for each HAP with a vapor pressure ≥ 0.6 kPa and by ≥ 60 percent for each HAP with a vapor pressure < 0.6 kPa.</p> <p>ii. Reduce emissions of each HAP with a vapor pressure ≥ 0.6 kPa by ≥ 75 percent by weight and each HAP with a vapor pressure < 0.6 kPa by ≥ 60 percent by weight by venting emissions through a closed-vent system to any combination of control devices (except a flare); or</p> <p>iii. Reduce emissions of total organic HAP by venting emissions from a non-halogenated vent stream through a closed-vent system to a flare; or</p> <p>iv. Reduce emissions of total organic HAP by venting emissions through a closed-vent system to a condenser that reduces the outlet gas temperature to:</p> <p>$< 10^{\circ}\text{C}$ if the process vessel contains HAP with a partial pressure < 0.6 kPa, or</p> <p>$< 2^{\circ}\text{C}$ if the process vessel contains HAP with a partial pressure ≥ 0.6 kPa and < 17.2 kPa, or</p> <p>$< -5^{\circ}\text{C}$ if the process vessel contains HAP with a partial pressure ≥ 17.2 kPa.</p>